

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)				Docket No. APPM/8349		Serial No. 10/672,420	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>				Applicant Nguyen, et al.		Confirmation No. Unknown	
(Use several sheets if necessary)				Filing Date September 26, 2003		Group Unknown	
Examiner Unknown							
<b>U.S. Patent Documents</b>							
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
N	A1	6,551,406	04/22/2003	Kilpi	118	728	12/27/2000
N	A2	6,511,539	01/28/2003	Raaijmakers	117	102	09/08/1999
N	A3	6,482,733	11/19/2002	Raaijmakers	438	633	04/26/2001
N	A4	6,482,262	11/19/2002	Elers, Et Al.	117	84	10/13/2000
N	A5	6,481,945	11/19/2002	Hasper, Et Al.	414	217	04/04/1999
N	A6	6,478,872	11/12/2002	Chae, Et Al.	117	88	12/20/1999
N	A7	6,475,910	11/05/2002	Sneh	438	685	09/22/2000
N	A8	6,475,276	11/05/2002	Elers, Et Al.	117	84	10/13/2000
N	A9	6,468,924	10/22/2002	Lee, Et Al.	438	763	05/31/2001
N	A10	6,451,695	09/17/2002	Sneh	438	685	12/22/2000
N	A11	6,451,119	09/17/2002	Sneh, Et Al.	118	715	11/29/2000
N	A12	6,447,607	09/10/2002	Soininen, Et Al.	117	200	12/27/2000
N	A13	6,428,859	08/06/2002	Chiang, Et Al.	427	457	03/19/2001
N	A14	6,416,822	07/09/2002	Chiang, Et Al.	427	561	03/19/2001
N	A15	6,416,577	07/09/2002	Suntola, Et Al.	117	88	12/09/1998
N	A16	6,399,491	06/04/2002	Jeon, Et Al.	438	680	04/06/2001
N	A17	6,391,785	05/21/2002	Satta, Et Al.	437	704	08/23/2000
N	A18	6,379,748	04/30/2002	Bhandari, Et Al.	427	255.394	01/17/2000
N	A19	6,372,598	04/16/2002	Kang, Et Al.	438	399	06/16/1999
N	A20	6,358,829	03/19/2002	Yoon, Et Al.	438	597	09/16/1999
N	A21	6,348,376	02/19/2002	Lim, Et Al.	438	253	01/19/2001
N	A22	6,342,277	01/29/2002	Sherman	427	562	04/14/1999
N	A23	6,306,216	10/23/2001	Kim, Et Al.	118	725	07/12/2000
N	A24	6,305,314	10/23/2001	Sneh, Et Al.	118	723	12/17/1999
N	A25	6,287,965	09/11/2001	Kang, Et Al.	438	648	02/23/2000
N	A26	6,284,646	09/04/2001	Leem	438	629	08/19/1998
Examiner <u>R</u>					Date Considered <u>9-16-05</u>		
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.							

U.S. Department of Commerce, Patent and Trademark Office				Docket No.		Serial No.	
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Applicant Nguyen, et al.		Confirmation No. Unknown	
(Use several sheets if necessary)				Filing Date		Group	
Examiner Unknown				September 26, 2003		Unknown	
U.S. Patent Documents							
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
✓	A27	6,270,572	08/07/2001	Kim, Et Al.	117	93	08/09/1999
✓	A28	6,231,672	05/15/2001	Choi, Et Al.	118	715	05/18/1999
✓	A29	6,207,487	03/27/2001	Kim, Et Al.	438	238	10/12/1999
✓	A30	6,203,613	03/20/2001	Gates, Et Al.	117	104	10/19/1999
✓	A31	6,200,893	03/13/2001	Sneh	438	685	03/11/1999
✓	A32	6,197,683	03/06/2001	Kang, Et Al.	438	643	09/18/1998
✓	A33	6,183,563	02/06/2001	Choi, Et Al.	118	715	05/18/1999
✓	A34	6,174,809	01/16/2001	Kang, Et Al.	438	682	12/15/1998
✓	A35	6,174,377	01/16/2001	Doering, Et Al.	118	729	01/04/1999
✓	A36	6,144,060	11/07/2000	Park, Et Al.	257	310	07/31/1998
✓	A37	6,139,700	10/31/2000	Kang, Et Al.	204	192.17	09/30/1998
✓	A38	6,124,158	09/26/2000	Dautartas, Et Al.	438	216	06/08/1999
✓	A39	6,084,302	07/04/2000	Sandhu	257	751	12/26/1995
✓	A40	6,042,652	03/28/2000	Hyun, Et Al.	118	719	09/07/1999
✓	A41	6,015,917	01/18/2000	Bhandari, Et Al.	556	12	01/23/1998
✓	A42	6,015,590	01/18/2000	Suntola, Et Al.	427	255.23	11/28/1995
✓	A43	5,923,056	07/13/1999	Lee, Et Al.	257	192	03/12/1998
✓	A44	5,916,365	06/29/1999	Sherman	117	92	08/16/1996
✓	A45	5,879,459	03/09/1999	Gadgli, Et Al.	118	715	08/29/1997
✓	A46	5,866,795	02/02/1999	Wang, et al.	73	1.36	03/17/1997
✓	A47	5,855,680	01/05/1999	Soininen, Et Al.	118	719	11/28/1995
✓	A48	5,835,677	11/10/1998	Li, Et Al.	392	401	10/03/1996
✓	A49	5,807,792	09/15/1998	Ilg, Et Al.	438	758	12/18/1996
✓	A50	5,796,116	08/18/1998	Nakata, Et Al.	257	66	08/18/1998
✓	A51	5,711,811	01/27/1998	Suntola, Et Al.	118	711	10/02/1996
✓	A52	5,674,786	10/07/1998	Turner, Et Al.	437	225	06/05/1995
Examiner <u>Re</u>					Date Considered <u>9-16-05</u>		
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✓	A53	5,503,875	04/02/1996	Imai, Et Al.	427	255.3	03/17/1994
✓	A54	5,483,919	01/16/1996	Yokoyama, Et Al	117	89	08/17/1994
✓	A55	5,480,818	01/02/1996	Matsumoto, Et Al.	437	40	02/09/1993
✓	A56	5,443,647	08/22/1995	Aucoin, Et Al.	118	723	07/11/1994
✓	A57	5,441,703	08/15/1995	Jurgensen	422	129	03/29/1994
✓	A58	5,374,570	12/20/1994	Nasu, Et Al.	437	40	08/19/1993
✓	A59	5,360,738	11/01/1994	Jones, et al.	436	30	04/16/1993
✓	A60	5,294,286	03/15/1994	Nishizawa, Et Al.	156	610	01/12/1993
✓	A61	5,281,274	01/25/1994	Yoder	118	697	02/04/1993
✓	A62	5,225,366	07/06/1993	Yoder	437	108	06/22/1990
✓	A63	4,993,357	02/19/1991	Scholz	118	715	12/21/1989
✓	A64	4,834,831	05/30/1989	Nishizawa, Et Al	156	611	09/04/1987
✓	A65	4,413,022	11/1/1983	Suntola, Et Al.	427	255.2	06/21/1979
✓	A66	4,389,973	06/28/1983	Suntola, Et Al.	118	725	12/11/1981
✓	A67	4,058,430	11/15/1977	Suntola, Et Al.	156	611	11/25/1975
✓	A68	2002/0009544	01/24/2002	McFeely, et al.	427	248.1	08/20/1999
✓	A69	20020082296	06/27/2002	Verschoor, Et Al.	514	557	05/02/2001
✓	A70	20030075925	04/24/2003	Lindfors, Et Al.	285	367	06/28/2002
✓	A71	20030075273	04/24/2003	Kilpela, Et Al.	156	345.33	08/14/2002
✓	A72	20030072975	04/17/2003	Shero, Et Al.	428	704	09/26/2002
✓	A73	20030049942	03/13/2003	Haukka, Et Al.	438	778	08/22/2002
✓	A74	20030042630	03/06/2003	Babcoke, Et Al.	261	121.1	09/05/2001
✓	A75	20030031807	02/13/2003	Elers, Et Al.	427	569	09/17/2002
✓	A76	20030013320	01/16/2003	Kim, Et Al.	438	778	05/31/2001
✓	A77	20030004723	01/02/2003	Chihara	704	260	01/29/2002
✓	A78	20020197402	12/26/2002	Chiang, Et Al.	427	255.39	08/05/2002

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✓	A79	20020187256	12/12/2002	Elers, Et Al.	427	99	07/30/2002
✓	A80	20020182320	12/05/2002	Leskela, Et Al.	427	250	03/15/2002
✓	A81	20020177282	11/28/2002	Song	438	300	12/18/2001
✓	A82	20020164423	11/17/2002	Chiang, Et Al.	427	255.28	05/03/2002
✓	A83	20020164421	11/07/2002	Chiang, Et Al.	427	248.1	05/03/2002
✓	A84	20020162506	11/07/2002	Sneh, Et Al.	118	715	06/28/2002
✓	A85	20020155722	10/24/2002	Satta, Et Al.	438	704	04/15/2002
✓	A86	20020146511	10/10/2002	Chiang, Et Al.	427	248.1	10/24/2001
✓	A87	20020144657	10/10/2002	Chiang, Et Al.	118	723 E	10/03/2001
✓	A88	20020144655	10/10/2002	Chiang, Et Al.	118	715	10/24/2001
✓	A89	20020134307	09/26/2002	Choi	118	715	11/30/2000
✓	<del>A90</del>	<del>2002008570</del>	<del>08/15/2002</del>	<del>Lindfors</del>	<del>118</del>	<del>715</del>	<del>04/16/2001</del>
✓	A91	20020106536	08/08/2002	Lee, Et Al.	428	702	02/02/2001
✓	A92	20020104481	08/08/2002	Chiang, Et Al.	118	723	03/19/2001
✓	A93	20020098627	07/25/2002	Pomarede, Et Al.	438	149	08/31/2001
✓	A94	20020094689	07/18/2002	Park	438	694	03/07/2002
✓	A95	20020092471	07/18/2002	Kang, Et Al.	118	715	01/16/2002
✓	A96	20020086106	07/04/2002	Park, Et Al.	427	248.1	11/07/2001
✓	A97	20020076837	06/20/2002	Hujanen, Et Al.	438	3	11/28/2001
✓	A98	20020076508	06/20/2002	Chiang, Et Al.	427	569	12/19/2001
✓	A99	20020076507	06/20/2002	Chiang, Et Al.	427	569	10/24/2001
✓	A100	20020076481	06/20/2002	Chiang, Et Al.	427	8	10/24/2001
✓	A101	20020073924	06/20/2002	Chiang, Et Al.	118	723 R	10/24/2001
✓	A102	20020068458	06/06/2002	Chiang, Et Al.	438	694	11/26/2001
✓	A103	20020066411	06/06/2002	Chiang, Et Al.	118	724	05/10/2001
✓	A104	20020052097	05/02/2002	Park	438	507	05/03/2001
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N	A105	20020048635	04/25/2002	Kim, Et Al.	427	331	10/08/1999
N	A106	20020041931	04/11/2002	Suntola, Et Al.	427	255.28	05/14/2001
N	A107	20020031618	03/14/2002	Sherman	427	569	10/09/2001
N	A108	20020021544	02/21/2002	Cho, Et Al.	361	200	08/07/2001
N	A109	20020020869	02/21/2002	Park, Et Al.	257	306	12/20/2000
N	A110	20020007790	01/24/2002	Park	118	715	05/03/2001
N	A111	20020000598	01/03/2002	Kang, Et Al.	257	301	07/26/2001
N	A112	20020000196	01/03/2002	Park	118	715	05/03/2001
N	A113	20010054769	12/27/2001	Raaijmakers, Et Al	257	758	04/26/2001
N	A114	20010054730	12/27/2001	Kim, Et Al.	257	301	05/23/2001
N	A115	20010054377	12/27/2001	Lindfors, Et Al.	117	104	04/16/2001
N	A116	20010042799	11/22/2001	Kim, Et Al.	239	553	02/02/2001
N	A117	20010042523	11/22/2001	Kesala	122	6.6	05/14/2001
N	A118	20010041250	11/15/2001	Werkhoven, Et Al.	428	212	03/06/2001
N	A119	20010034123	10/25/2001	Jeon, Et Al.	438	643	04/06/2001
N	A120	20010028924	10/11/2001	Sherman	427	255.28	05/24/2001
N	A121	20010025979	10/04/2001	Kim, Et Al.	257	315	12/04/2000
N	A122	20010024387	09/27/2001	Raaijmakers, Et Al	365	200	02/22/2001
N	A123	20010014371	08/16/2001	Kilpi	427	255.28	12/27/2000
N	A124	20010013312	08/16/2001	Soininen, Et Al.	117	86	12/27/2000
N	A125	20010011526	08/09/2001	Doering, Et Al.	118	729	01/16/2001
N	A126	20010009695	07/26/2001	Saanila, Et Al.	427	255.39	01/18/2001
N	A127	20010009140	07/26/2001	Bondestan, Et Al.	118	725	01/25/2001
N	A128	20010002280	05/31/2001	Sneh	427	255.28	12/22/2000
N	A129	20010000866	05/10/2001	Sneh, Et Al.	118	723	11/29/2000
N	A130						
Examiner <i>R</i>				Date Considered <i>9-16-05</i>			
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	A131					
	A132					
	A133					
	A134					

## Foreign Patent Documents

*Examine r Initial		Document Number	Date	Country	Class	Subclass	Translation	
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N	B1	WO 02/45167	06/06/2002	WO	H01L	27/00	<input type="checkbox"/>	<input checked="" type="checkbox"/>
N	B2	WO 02/43115	05/30/2002	WO	H01L		<input type="checkbox"/>	<input checked="" type="checkbox"/>
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N	B8	WO 01/29891	04/26/2001	WO	H01L	21/768	<input type="checkbox"/>	<input checked="" type="checkbox"/>
N	B9	WO 01/29280	04/26/2001	WO	C23C	16/32	<input type="checkbox"/>	<input checked="" type="checkbox"/>
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**For Ign Patent Documents**

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N	B20	WO 96/17107	06/06/1996	WO	C23C	16/44	<input type="checkbox"/>	<input checked="" type="checkbox"/>
N	B21	58098917	06/10/1983	JP	H03J	7/02	<input type="checkbox"/>	<input checked="" type="checkbox"/>
N	B22	2001172767 (w/ English Abstract)	06/26/2001	JP	C23C	16/40	<input type="checkbox"/>	<input checked="" type="checkbox"/>
N	B23	2001111000	04/20/2001	JP	H01L	27/105	<input type="checkbox"/>	<input checked="" type="checkbox"/>
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N	B25	2000319772 (Abstract Only)	03/28/2000	JP	C23C	16/00	<input type="checkbox"/>	<input checked="" type="checkbox"/>
N	B26	6224138 (Abstract Only)	05/31/1994	JP	C30B	25/14	<input type="checkbox"/>	<input checked="" type="checkbox"/>
N	B27	5270997 (Abstract Only)	10/19/1993	JP	C30B	29/68	<input type="checkbox"/>	<input checked="" type="checkbox"/>
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N	B29	5206036 (Abstract Only)	08/13/1993	JP	H01L	21/205	<input type="checkbox"/>	<input checked="" type="checkbox"/>
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N	B31	4291916 (Abstract Only)	09/23/1992	JP	C30B	25/10B	<input type="checkbox"/>	<input checked="" type="checkbox"/>
N	B32	1 167 569	01/02/2002	EP	C23C	16/455	<input type="checkbox"/>	<input checked="" type="checkbox"/>
N	B33	2 355 727	05/02/2001	GB	C23C	16/44	<input type="checkbox"/>	<input checked="" type="checkbox"/>

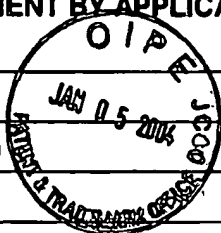
**OTHER ART**

*Examine r Initial		Including Author, Title, Date, Pertinent Pages, Etc.
N	C1	J.P. Stagg, J. Christer, E. J. Thrush and J. Crawley, "Measurement and Control of Reagent Concentrations in MOCVD Reactor Using Ultrasonics," Journal of Crystal Growth 120(1992) Pages 98-102
N	C2	"MultiGas™ 2030," MKS Instruments, Inc., Bulletin 2030-04/02

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Examiner Unknown			



OTHER ART			
*Examine r Initial		Including Author, Title, Date, Pertinent Pages, Etc.	
K	C3	Kukli, <i>et al.</i> , "Tailoring the Dielectric Properties of HfO <sub>2</sub> -Ta <sub>2</sub> O <sub>5</sub> Nanolaminates," Applied Physics Letters, Vol. 68, No. 26, June 24, 1996; p. 3737-9	
K	C4	Kukli, <i>et al.</i> "Atomic Layer Epitaxy Growth of Tantalum Oxide Thin Films from Ta(OC <sub>2</sub> H <sub>5</sub> ) <sub>5</sub> and H <sub>2</sub> O," Journal of the Electrochemical Society, Vol. 142, No. 5, May 1995; p. 1670-5	
K	C5	Kukli, <i>et al.</i> , "In situ Study of Atomic Layer Epitaxy Growth of Tantalum Oxide Thin Films From Ta(OC <sub>2</sub> H <sub>5</sub> ) <sub>5</sub> and H <sub>2</sub> O," Applied Surface Science, Vol. 112, March 1997, p. 236-42	
K	C6	Kukli, <i>et al.</i> , "Properties of Ta <sub>2</sub> O <sub>5</sub> -Based Dielectric Nanolaminates Deposited by Atomic Layer Epitaxy," Journal of the Electrochemical Society, Vol. 144, No. 1, Jan. 1997; p. 300-6	
K	C7	Kukli, <i>et al.</i> , "Properties of {Nb <sub>1-x</sub> Ta <sub>x</sub> } <sub>2</sub> O <sub>5</sub> Solid Solutions and {Nb <sub>1-x</sub> Ta <sub>x</sub> } <sub>2</sub> O <sub>5</sub> -ZrO <sub>2</sub> Nanolaminates Grown by Atomic Layer Epitaxy," 1997; p. 785-93	
K	C8	Ritala, M., <i>et al.</i> , "Chemical Vapor Deposition," January 1999, p. 6-9	
K	C9	Rossnagel, <i>et al.</i> "Plasma-enhanced Atomic Layer Deposition of Ta and Ti for Interconnect Diffusion Barriers," J. Vac. Sci. Technol. B., Vol. 18, No. 4 (July 2000); p2016-20	
K	C10	Niinisto, <i>et al.</i> "Synthesis of Oxide Thin Films and Overlayers by Atomic Layer Epitaxy for Advanced Applications," Materials Science and Engineering B41 (1996) 23-29	
K	C11	Eisenbraun, <i>et al.</i> "Atomic Layer Deposition (ALD) of Tantalum-based materials for zero thickness copper barrier applications," Proceedings of the IEEE 2001 International Interconnect Technology Conference (Cat. No. 01EX461) 2001	
K	C12	Clark-Phelps, <i>et al.</i> "Engineered Tantalum Aluminate and Hafnium Aluminate ALD Films for Ultrathin Dielectric Films with Improved Electrical and Thermal Properties," Mat. Res. Soc. Symp. Proc. Vol. 670 (2001)	
	C13		
	C14		
	C15		
Examiner <u>Ra</u>		Date Considered <u>9-16-05</u>	

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.